

**TEST AND BURN-IN APPARATUS, IN-LINE SYSTEM USING THE
APPARATUS, AND TEST METHOD USING THE SYSTEM**

ABSTRACT OF THE DISCLOSURE

An apparatus for testing semiconductor devices which allows various tests including burn-in at the same stage. The apparatus employs the same test trays, each of which contains the devices, without loading/unloading to device trays in between the various tests, so that
5 the apparatus can occupy less space. An in-line system is constructed by the apparatuses and provides a single sort step after all testing steps. Furthermore, a method for testing the devices is provide with the in-line system. In the method, the testing steps, time, and space are reduced by means of an employment of test tray maps corresponding to the test trays.
(Fig. 5)